Software for Modeling of Long-Term Growth of Bulk AIN Crystals by Physical Vapor Transport





VR-PVT AIN

STR-Group Ltd 2014



STR Virtual Reactor (VR) is a **family** of stand-alone 2D software tools designed for the simulation of long-term growth of bulk crystals and epilayers from vapor

Virtual Reactor editions:

Physical Vapor Transport

- For growth of SiC: VR-PVT SiC
- For growth of AIN: **VR-PVT AIN**

Hydride Vapor Phase Epitaxy: HEpiGaNS

- For growth of **GaN**
- For growth of **AIN** and **AIGaN**

Chemical Vapor Deposition

• For growth of SiC: VR-CVD SiC

VR-PVT AIN — Key Features

- VR-PVT AIN is specially designed for the modeling of long-term AIN bulk crystal growth by the seeded sublimation technique
- Account of non-steady character of the growth process (crystal enlargement, heater or crucible movement, etc.)
- Modeling of the heat transfer in the overall growth system
- Modeling of multicomponent flow
- · Modeling of diffusion of the reactive species in the growth chamber
- Advanced models of heterogeneous chemical reactions
- Prediction of material losses
- Estimation of the internal pressure inside the crucible
- Analysis of dislocation evolution
- Analysis of heat and mass transport in the porous source



Global Heat Transfer in an AIN Growth System

- Heat transfer mechanisms
 - Heat conduction in anisotropic media
 - Radiation
 - Convection
- RF heating with non-uniform heat distribution in the crucible by a single coil or two independent coils
- Heat transfer in porous source
- Heat transfer in thermal insulation
- Temperature fitting at a reference point



Simulation of the Heat Transfer in Porous AIN Source

Virtual Reactor employs an advanced model of the heat transfer in porous media

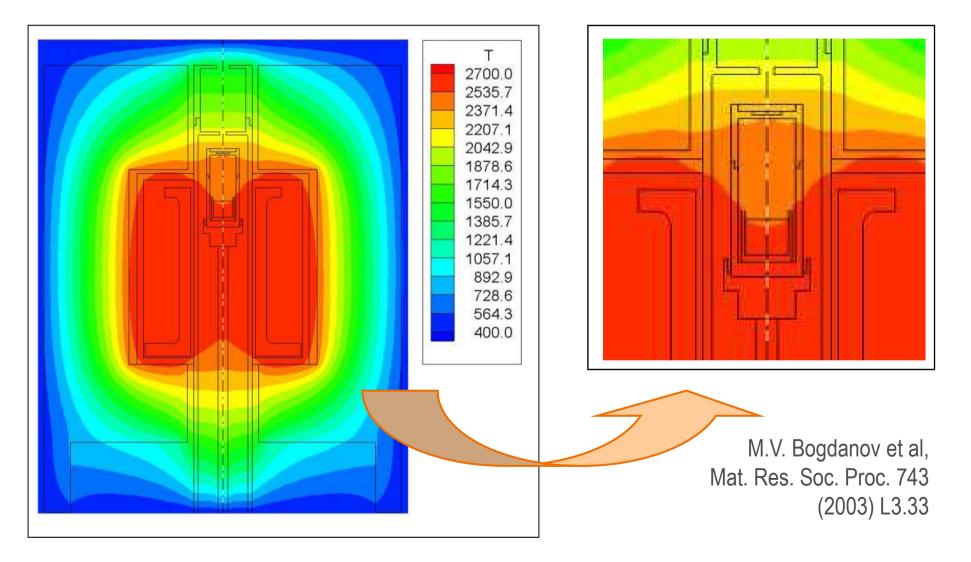
Key Features

- Heat conduction through the granule contact spots
- Radiation transport though the pores
- Radiation transport through the granules

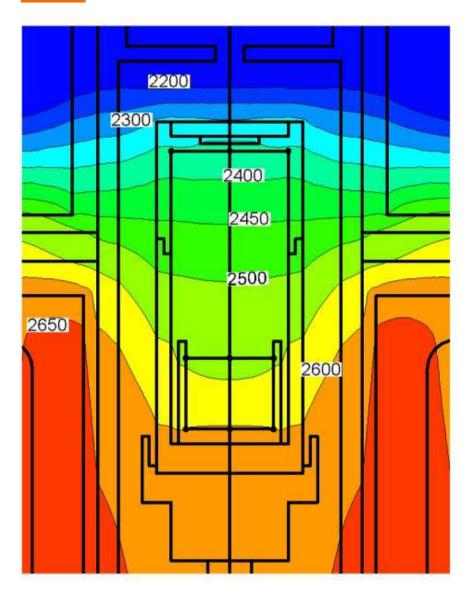
E.L. Kitanin et al., Mat. Sci. Engng. B55 (1998) 174



Temperature Distribution in an AIN Growth System







Temperature Distribution in the Crucible

M.V. Bogdanov et al, Mat. Res. Soc. Proc. 743 (2003) L3.33



Modeling of Species Transport in AIN Crystal Growth

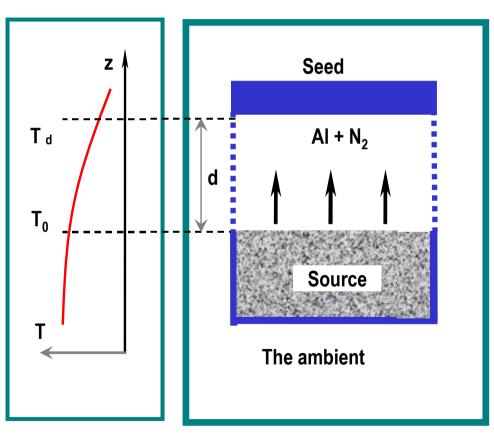
Use of the advanced models of species transport and heterogeneous processes in the sublimation growth of bulk AIN crystals

Employment of the material database containing accurate data on materials thermal conductivity



Mechanisms of Bulk AIN Crystal Growth

- Multicomponent vapor flow
- Diffusion of reactive species
- Heterogeneous reactions on the seed and source surfaces
- Stefan flow
- Mass exchange between the growth cell and the ambient



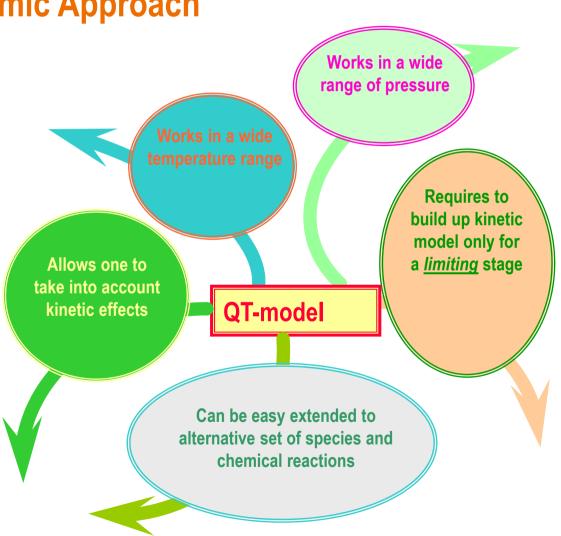


Quasi-Thermodynamic Approach

VR employs the quasithermodynamic model for the description of heterogeneous processes

S.Yu. Karpov et al., MRS Int. J. Nitr. Sem. Res. 4 (1999) 4

A.S.Segal et al, J. Crystal Growth 211 (2000) 68





Basic Assumptions

- Gaseous species: AI, N₂
- Reaction: **2** AI + N₂ = **2** AIN (solid)
- The atoms in the adsorption layer are nearly in thermodynamic equilibrium with the crystal: atom incorporation and desorption rates are much higher than their difference, i.e. the crystal growth rate
- Kinetics effects at the adsorption /desorption stages are accounted for by sticking/evaporation coefficients of the species

Species molar fluxes:

$$\boldsymbol{J}_i = \boldsymbol{\beta}_i \left(\boldsymbol{p}_i - \boldsymbol{p}_i^0 \right) \quad \text{i=AI, N_2}$$

$$\beta_i = \sqrt{\frac{1}{2\pi M_i RT}}$$
 - the Hertz-Knudsen factor

 p_i^0 - i-th species partial pressure p_i^0 - i-th species equilibrium pressure

Mass action law for the equilibrium pressures:

 $(p_{Al}^0)^2 p_{N_2}^0 = K(T)$ K(T) - equilibrium constant

Stoichiometric incorporation:

$$J_{Al} = 2J_{N_2} = \frac{\rho_{cr}}{M_{cr}}V_{gr}$$

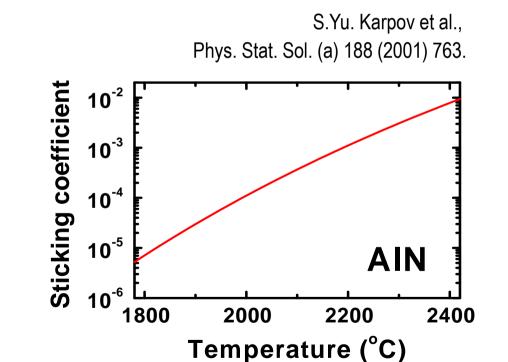
$${
m
ho}_{cr}$$
 - crystal density
 ${
m M}_{cr}$ - crystal molar mass
 ${
m V}_{gr}$ - growth rate



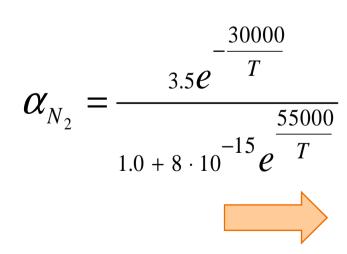
Adsorption Kinetics on AIN Surfaces

Aluminum adsorption kinetics:

 $\alpha_{Al} = 1$

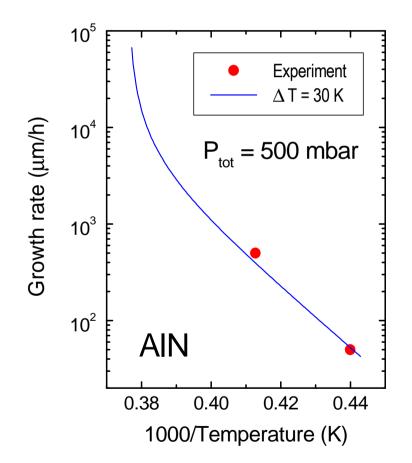


Nitrogen adsorption kinetics:





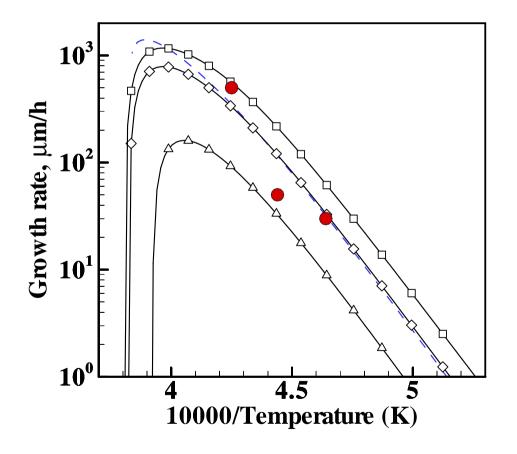
AIN Growth in the Nitrogen Atmosphere



Experiments: C.M. Balkas et al, Mat. Res. Sos. Symp. Proc. 449 (1997) 41.



AIN Growth in the Nitrogen Atmosphere



Solid circles: experimental data obtained at ΔT = 70 K

Solid curves - computations accounting for the mass exchange with the external ambient for different ΔT :

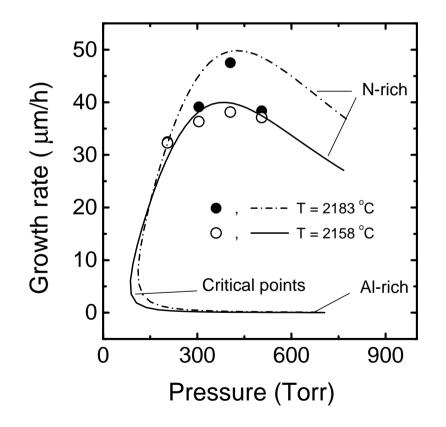
- Squares: $\Delta T = 100 \text{ K}$
- Diamonds: $\Delta T = 70 \text{ K}$
- Triangles: $\Delta T = 30 \text{ K}$

Dashed curve: theoretical predictions of the model for ΔT = 70 K

Experiments: C.M. Balkas et al, Mat. Res. Sos. Symp. Proc. 449 (1997) 41.



Growth Rate Limitation by the N₂ Adsorption Kinetics

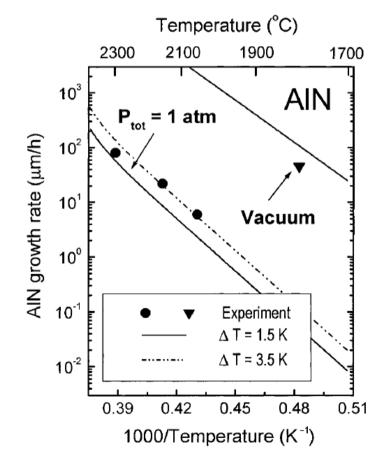


Computed and experimental AIN growth rates as a function of pressure at 2158°C and 2183°C. The clearance between the source and seed and the respective temperature difference are 4 mm and 4.5°C.

Experimental data obtained by M. Spencer



Growth Rate vs. Seed Temperature

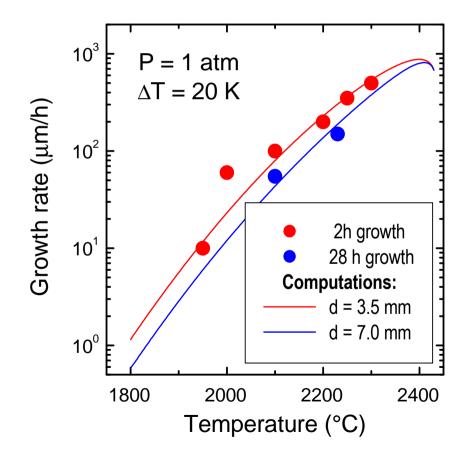


Computed and experimental AIN growth rates as a function of the seed temperature. Clearance d = 4 mm

S.Yu. Karpov et al., Phys. Stat. Sol. (a) 176 (1999) 435.



AIN Growth Rate at Different Growth Stages

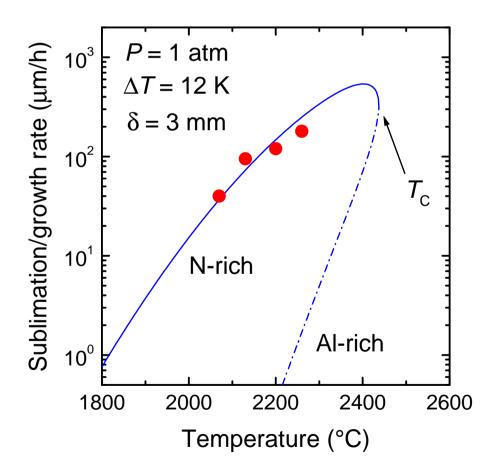


Circles: experiments Lines: computations

E.N. Mokhov et al, Mat. Sci. Forum 433-436 (2003) 979



Growth Rate vs. Seed Temperature



Circles: experiments Lines: computations

S.Yu. Karpov et al, Mat. Sci. Forum 353-356 (2001) 779

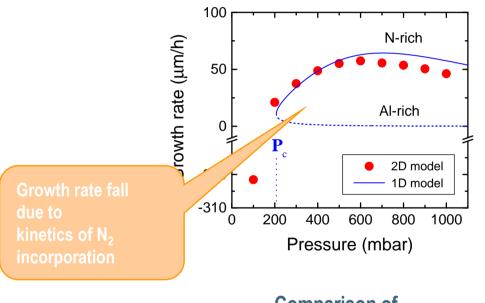
Experimental data by Yu.A. Vodakov et al.

(a)

(b)



Growth of AIN Close to Critical Pressure



Comparison of 1D and 2D Computations

Gas flow (right) and Al distribution (left)

AIN powder source

Seed surface

AIN powder source

Seed surface

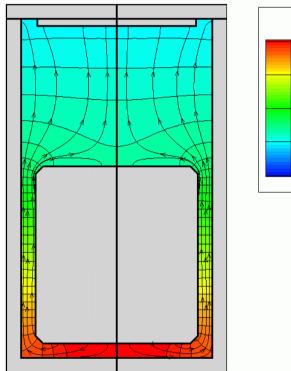
 $\mathbf{P} > \mathbf{P}_{c}$

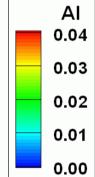
 $\mathbf{P} < \mathbf{P}_{c}$

S.Yu. Karpov et al, Mat. Sci. Forum 353-356 (2001) 779 Experimental data by Yu.A. Vodakov et al.

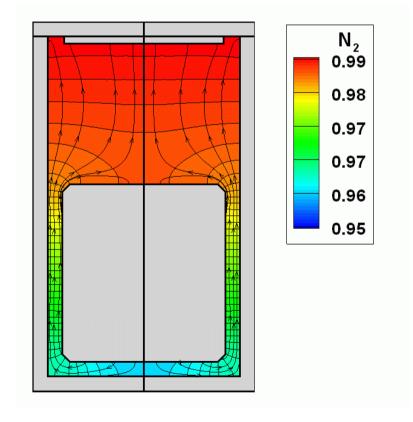


Flow Pattern and Species Distribution in the Growth Chamber



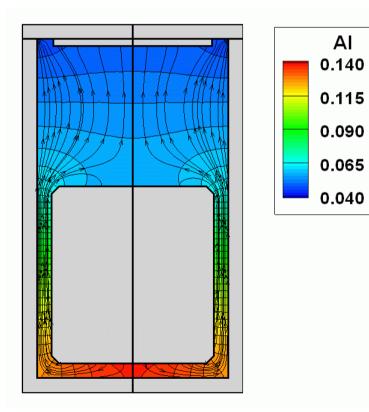


High pressure: **P** = 600 mbar

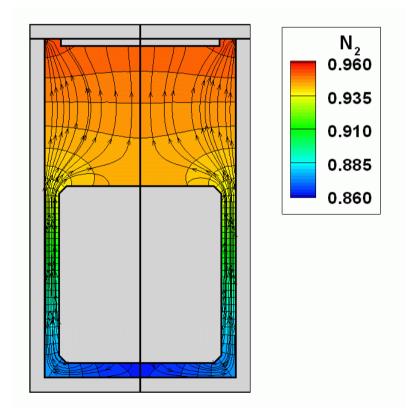




Flow Pattern and Species Distribution in the Growth Chamber

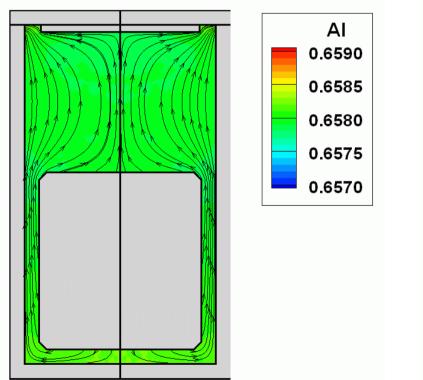


Medium pressure: P = 250 mbar

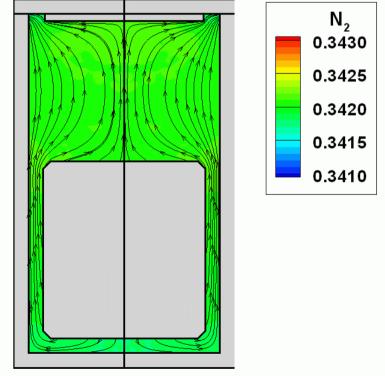




Flow Pattern and Species Distribution in the Growth Chamber



Very low pressure: P = 45 mbar

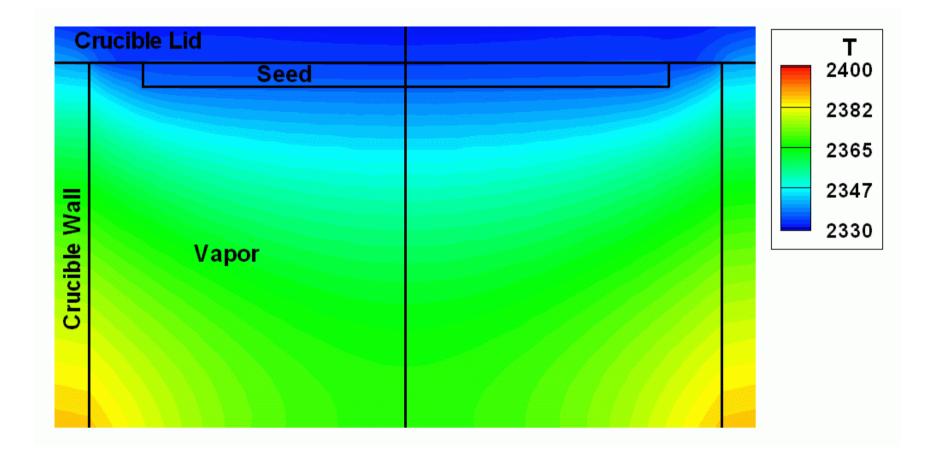




Simulation of Crystal Shape Evolution

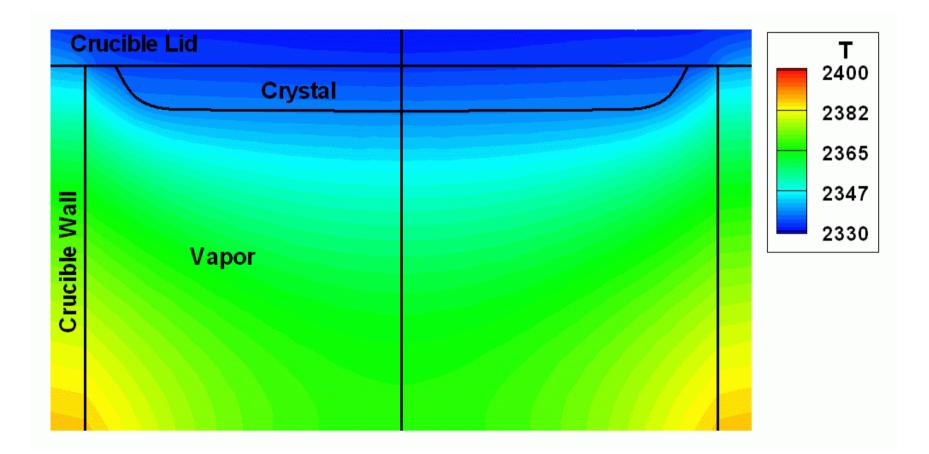
Pressure = 600 mbar

Start of the growth

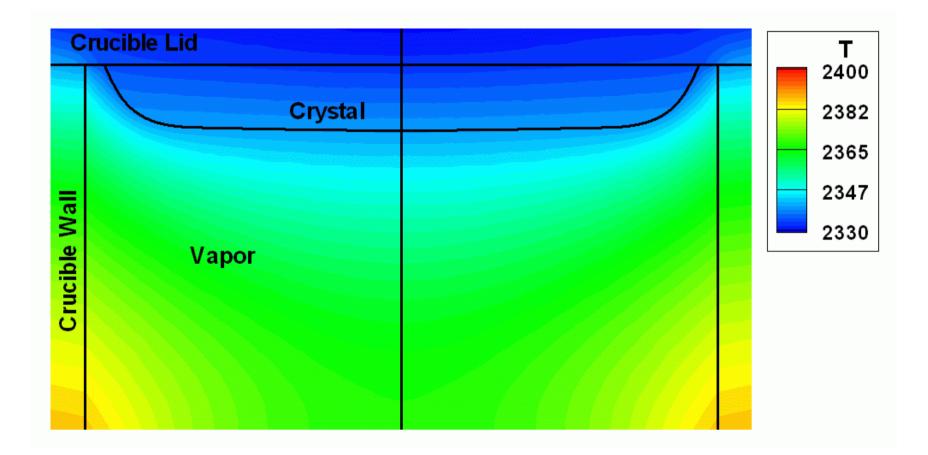




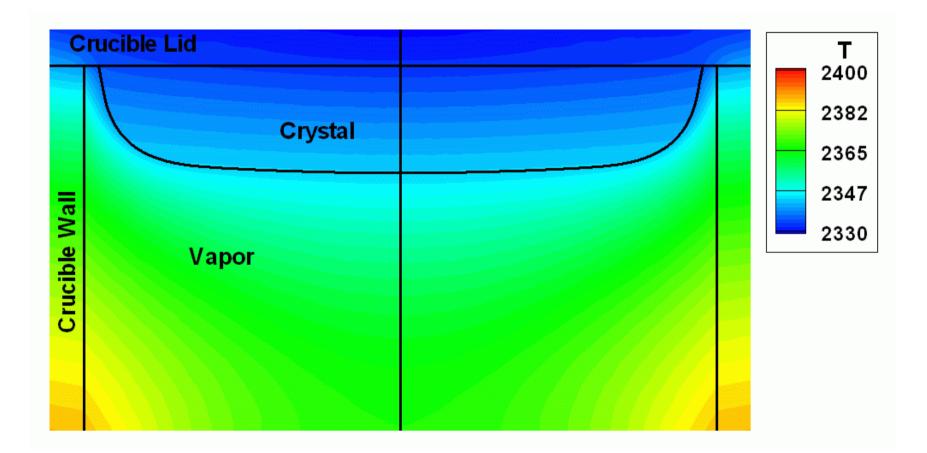
t = 5 h



t = 10 h

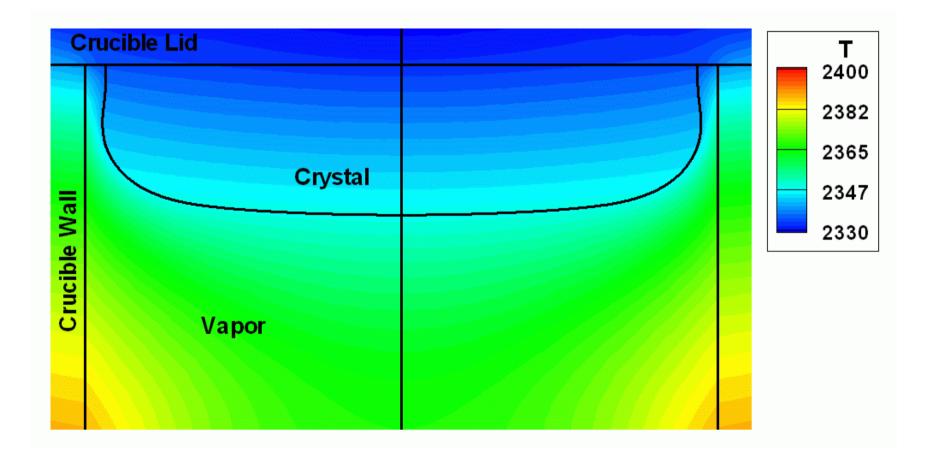


t = 20 h



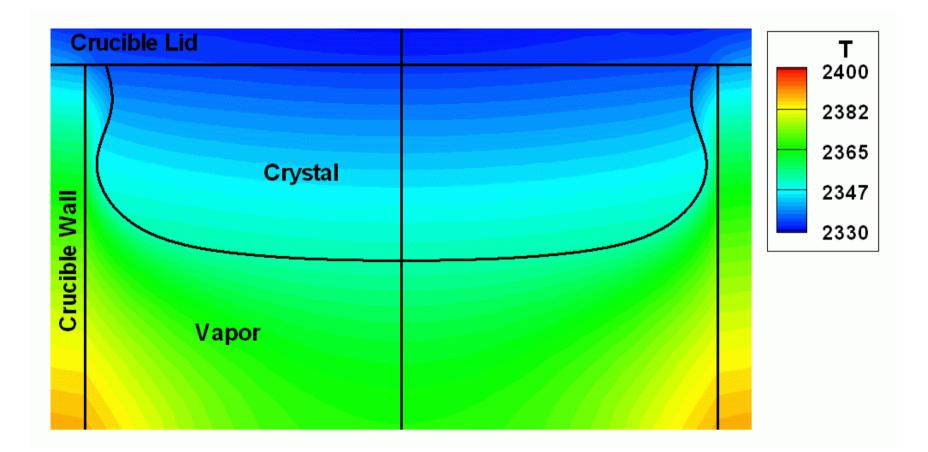


t = 30 h



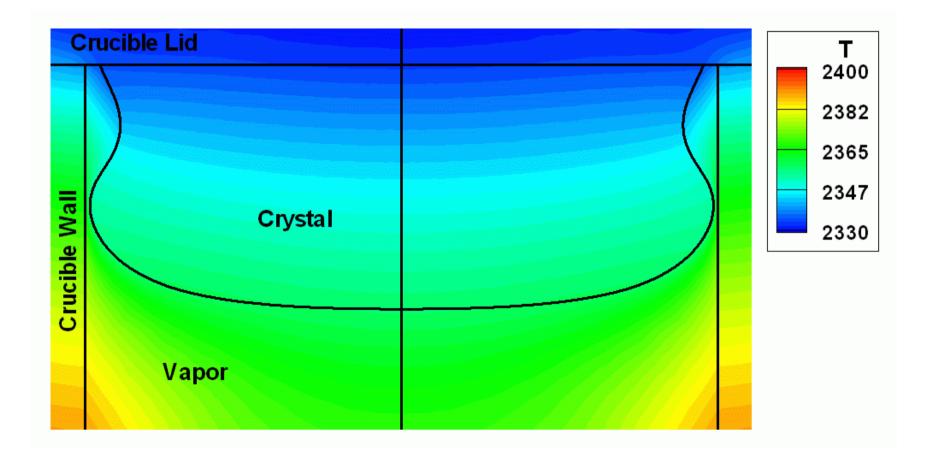


t = 40 h





t = 50 h





Species Transport in the Porous Source



Processes Observed in the Porous Source during the Growth

- Complete evaporation of the hot zones
- Densification of the source in the cold zones along with the secondary crystallization from the supersaturated vapor
- Directional gas flow through the porous source. In particular, this results in modification of granule shapes due to their sublimation and secondary crystallization of the reactive species



Basic Concepts

- AIN source is considered as porous medium characterized by
 - Local porosity
 - Granule size
- Species transport in the source is modeled using the Darcy-Brinkman-Forchheimer approach
- The account of the volumetric mass source due to chemical reactions on the surface of AIN granules
- Temporal variation of the porosity and granule size due to granule sublimation and recrystallization



Governing Equations

The source porosity: $\varepsilon = \frac{V_{fluid}}{V_{cell}}$

The continuity equations for the whole vapor:

The continuity equations for each species:

$$\nabla \cdot (\rho V) = S^m$$

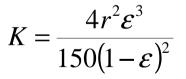
 (\rightarrow)

$$\nabla \cdot \left(\rho C_i \vec{V} + J_i \right) = S_i^m$$

Flow in the porous medium is described by the Darcy-Brinkman-Forchheimer law:

$$\frac{1}{\varepsilon}\nabla\cdot\left(\frac{1}{\varepsilon}\rho\vec{V}\vec{V}\right) = -\nabla p - \frac{\mu}{K}\vec{V} + \nabla\cdot\tau - \frac{\rho C_F}{\sqrt{K}}\left|\vec{V}\right|\vec{V} - \rho\vec{g}$$

The porous medium permeability and inertial coefficient are found from the granule radius and porosity using Ergun's relationship:



$$C_F = \frac{1.75}{\sqrt{150}} \varepsilon^{-3/2}$$



Boundary Conditions on the Source-Gas Interface:

The gas velocity:	$\left. ec{V} ight _{b^{-}} = ec{V} ight _{b^{+}}$
Pressure:	$p\big _{b^-} = p\big _{b^+}$
Viscous stress tensor:	$\left. au \cdot ec{n} ight _{b^{-}} = au \cdot ec{n} ight _{b^{+}}$
Species:	$\left(\rho V_n C_i + J_i\right)_{b^+} = \left(\rho V_n C_i + J_i\right)_{b^-}$



Modeling of the Porous Source Evolution

Temporal variation of the granule size:

 $\frac{dr}{dt} = -V_{subl}$, where V_{subl} is the sublimation rate

Relationship between the porosity and the granule size:

 ${\cal E}=e^{-\eta}$, where $\,\eta$ is the reduced density defined as $\,\eta$

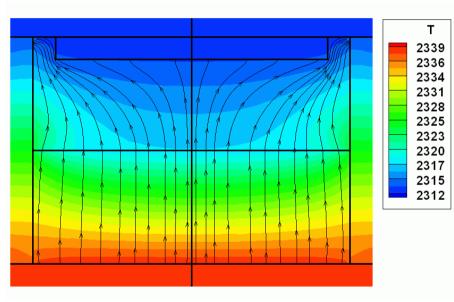
$$\eta = \frac{4}{3}\pi r^3 n_{gr}$$

The granule concentration assumed to be constant during the growth:

$$n_{gr} = -\frac{3\ln \varepsilon|_{t=0}}{4\pi \left(r|_{t=0}\right)^3}$$

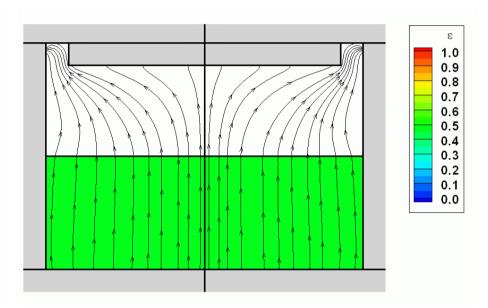


Start of the growth



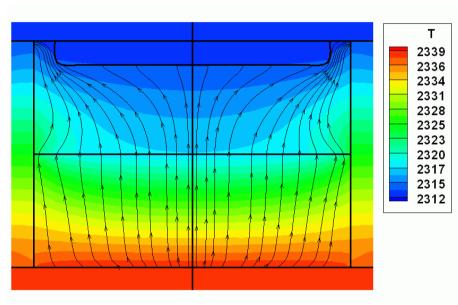
Temperature distribution and the flow pattern in the source and gas chamber

Initial porosity = 0.5



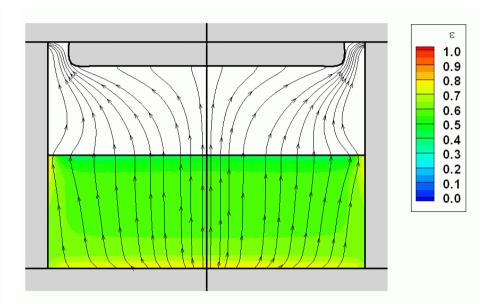


t = 2 h



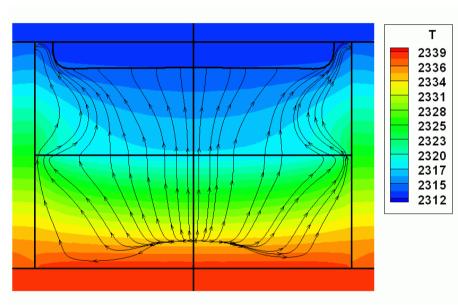
Temperature distribution and the flow pattern in the source and gas chamber

Initial porosity = 0.5

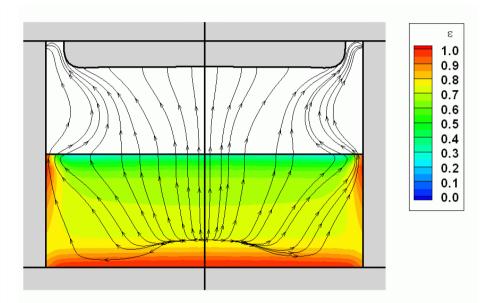




t = 5 h

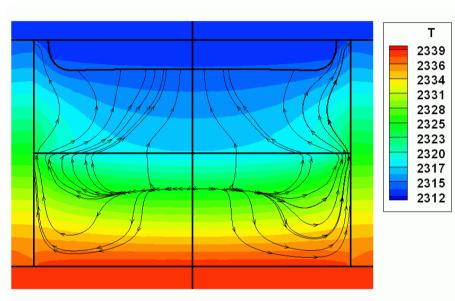


Temperature distribution and the flow pattern in the source and gas chamber Initial porosity = 0.5



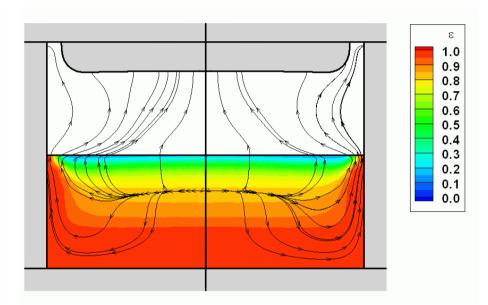


t = 10 h



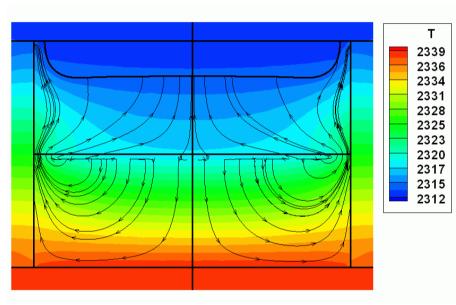
Temperature distribution and the flow pattern in the source and gas chamber

Initial porosity = 0.5



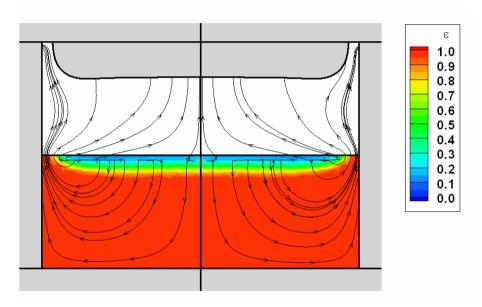


t = 20 h



Temperature distribution and the flow pattern in the source and gas chamber

Initial porosity = 0.5





Main Results:

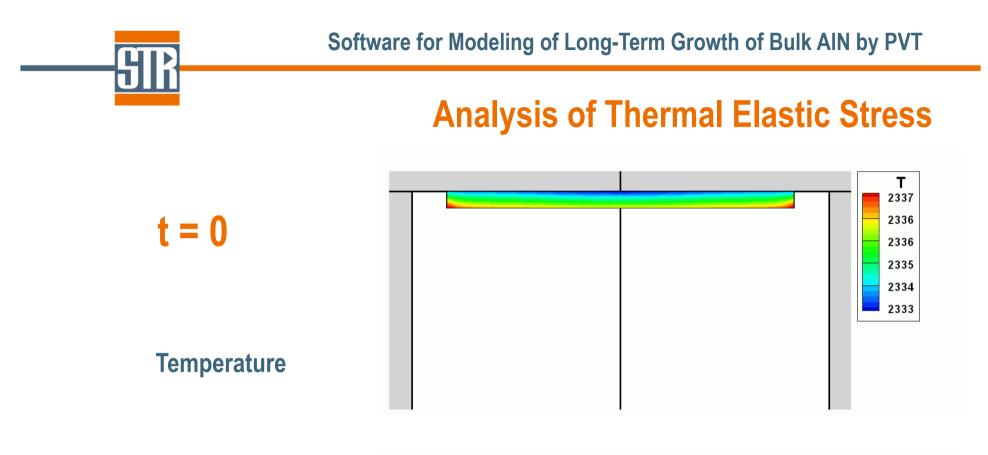
✓ Zone of active sublimation in the porous source is initially localized at the hot area and moves into the source bulk while the hot zones completely sublime

✓ Reduced porosity zones are formed in relatively cold regions



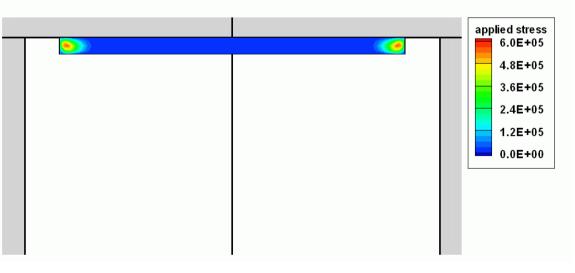
Analysis of Thermal Elastic Stress and Dislocation Evolution. Basic Features

- Finite-element analysis of the thermal elastic stress in AIN crystals
- Evaluation of the density of the dislocations gliding in the basal (0001) plane on the assumption of a full stress relaxation due to plastic deformation (S.Yu. Karpov et al., *J.Cryst. Growth* 211 (2000) 347)



Applied Stress

(Magnitude of σ_{rz} Stress Component)





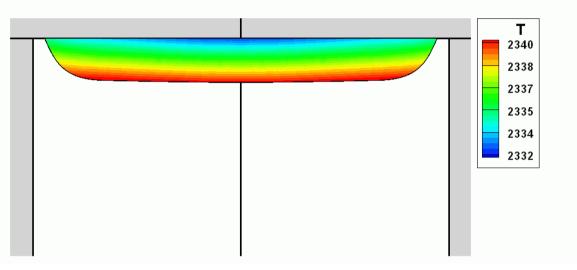
Software for Modeling of Long-Term Growth of Bulk AIN by PVT

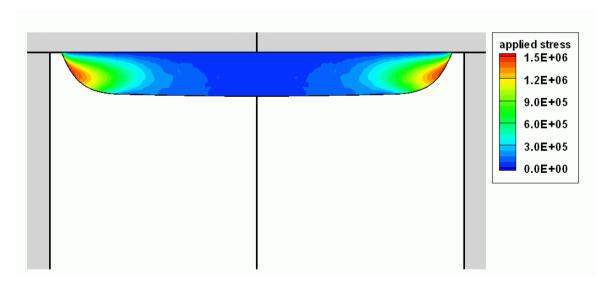
Analysis of Thermal Elastic Stress



Temperature

Applied Stress

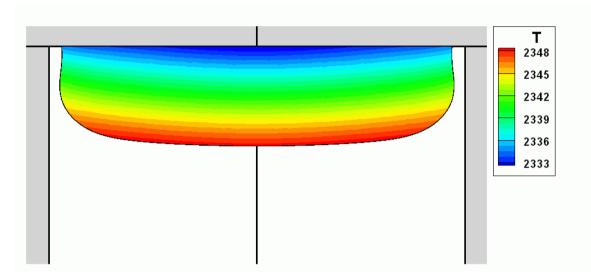






Software for Modeling of Long-Term Growth of Bulk AIN by PVT

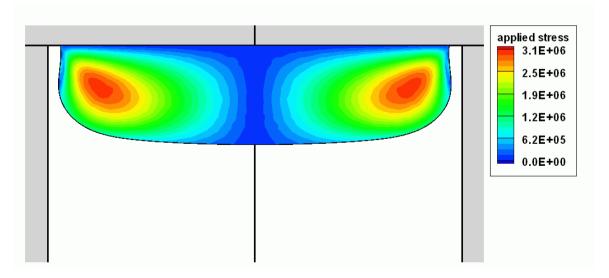
Analysis of Thermal Elastic Stress



t = 30

Temperature

Applied Stress



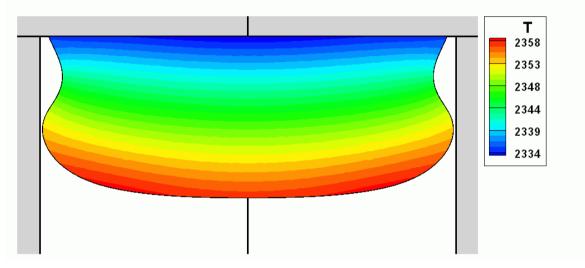


Software for Modeling of Long-Term Growth of Bulk AIN by PVT

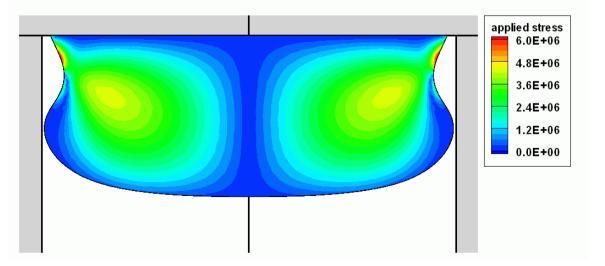
Analysis of Thermal Elastic Stress



Temperature

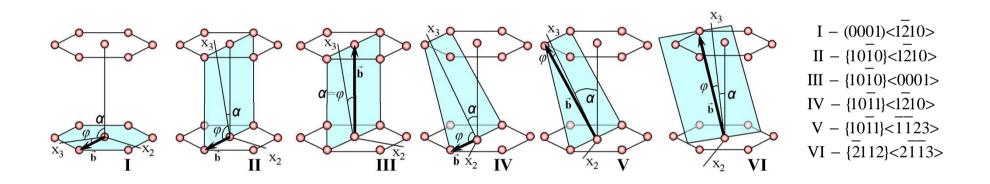








Analysis of Threading Dislocation Dynamics. Principal Slip Systems in a Hexagonal Crystal



Virtual Reactor predicts propagation of dislocations of **II** (prismatic) and of **III** (screw) type frequently observed in the growing bulk crystal



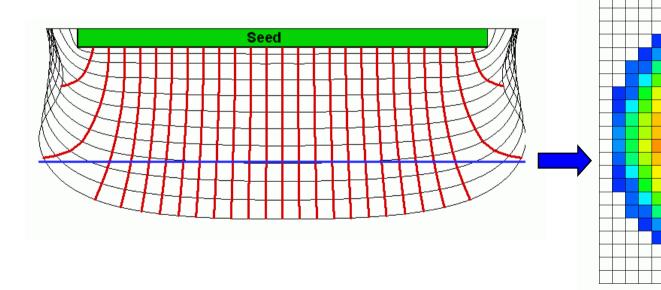
Analysis of Threading Dislocation Dynamics. Prismatic Dislocations

 $\{10\overline{1}0\} < 1\overline{2}10 >$

N^{Prism} 10000

Dislocation traces in bulk crystal growth

Wafer mapping



Dislocation density, cm⁻²



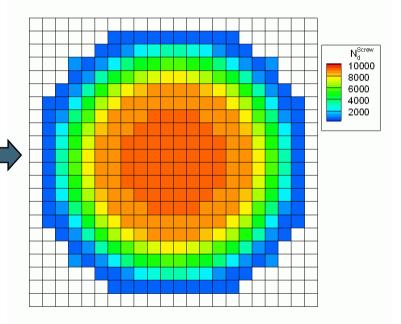
Analysis of Threading Dislocation Dynamics. Screw Dislocations

 $\{10\overline{1}0\} < 0001 >$

Dislocation traces in bulk crystal growth

Seed





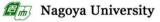
Dislocation density, cm⁻²

Some VR users in Europe



Some VR users in South-East Asia









Amano

SKC

BRIDGESTONE













哈爾濱ノ業大學 HARBIN INSTITUTE OF TECHNOLOGY



Shir Etsu







OC

Institute of Semiconductors Chinese Academy of Sciences













Publications

- M.V. Averyanova, S.Yu. Karpov, Yu.N. Makarov, M.S. Ramm, R.A. Talalaev, Theoretical model for analysis and optimization of group III-nitrides growth by molecular beam epitaxy. MRS Internet Journal of Nitride Semiconductor Research 1, Art.31, (1996)
- M.V. Averyanova, I.N. Przhevalskii, S.Yu. Karpov, Yu.N. Makarov, M.S. Ramm, R.A. Talalaev, Analysis of vaporization kinetics of group-III nitrides. Materials Science and Engineering B43, p.167-171, (1997)
- S.Yu. Karpov, Yu.N. Makarov, M.S. Ramm, The role of gaseous species in group-III nitride growth. MRS Internet Journal of Nitride Semiconductor Research 2, Art.45, (1997)
- S.Yu. Karpov, Yu.N. Makarov, M.S. Ramm, R.A. Talalaev, Control of SiC growth and graphitization in sublimation sandwich system. Materials Science and Engineering B46, p.340-344, (1997)
- S.Yu. Karpov, D.V. Zimina, Yu.N. Makarov, E.N. Mokhov, A.D. Roenkov, M.G. Ramm, Yu.A. Vodakov, Sublimation growth of AIN in vacuum and in a gas atmosphere. Physica Status Solidi (a) 176, p.435-438, (1999)
- I.A. Zhmakin, A.V. Kulik, S.Yu. Karpov, S.E. Demina, M.S. Ramm, Yu.N. Makarov, Evolution of thermoelastic strain and dislocation density during sublimation growth of silicon carbide. Diamond and Related Materials 9, p.446-451, (2000)



Publications (continued)

- A.S. Segal, S.Yu. Karpov, Yu.N. Makarov, E.N. Mokhov, A.D. Roenkov, M.G. Ramm, Yu.A. Vodakov, On mechanisms of sublimation growth of AIN bulk crystals. Journal of Crystal Growth 211, p.68-72, (2000)
- M.V. Bogdanov, A.O. Galyukov, S.Yu. Karpov, A.V. Kulik, S.K. Kochuguev, D.Kh. Ofengeim, A.V. Tsirulnikov, M.S. Ramm, A.I. Zhmakin, Yu.N. Makarov, Virtual reactor as a new tool for modeling and optimization of SiC bulk crystal growth. Journal of Crystal Growth 225, p.307-311, (2001)
- M.V. Bogdanov, A.O. Galyukov, S.Yu. Karpov, A.V. Kulik, S.K. Kochuguev, D.Kh. Ofengeim, A.V. Tsirulnikov, I.A. Zhmakin, A.E. Komissarov, O.V. Bord, M.S. Ramm, A.I. Zhmakin, Yu.N. Makarov, Virtual reactor: a new tool for SiC bulk crystal growth study and optimization. Materials Science Forum 353-356, p.57-60, (2001)
- S.Yu. Karpov, A.V. Kulik, M.S. Ramm, E.N. Mokhov, A.D. Roenkov, Yu.A. Vodakov, Yu.N. Makarov, AIN crystal growth by sublimation technique. Materials Science Forum 353-356, p.779-782, (2001)
- S.Yu. Karpov, A.V. Kulik, A.S. Segal, M.S. Ramm, Yu.N. Makarov, Effect of reactive ambient on AIN sublimation growth. Physica Status Solidi (a) 188, p.763-767, (2001)
- M.V. Bogdanov, S.Yu. Karpov, A.V. Kulik, M.S. Ramm, Yu.N. Makarov, R. Schlesser, R.F. Dalmau, Z. Sitar, Experimental and theoretical analysis of heat and mass transport in the system for AIN bulk crystal growth. Materials Research Society Symposium Proceedings 743, p.L3.33, (2003)



Publications (continued)

- M.V. Bogdanov, S.E. Demina, S.Yu. Karpov, A.V. Kulik, M.S. Ramm, Yu.N. Makarov, Advances in modeling of widebandgap bulk crystal growth, *Cryst. Res. Technol.* 38, p.237-249, (2003)
- S.Yu. Karpov, A.V. Kulik, I.N. Przhevalskii, M.S. Ramm, and Yu.N. Makarov Role of oxygen in AlN sublimation growth, *Phys. Stat. Sol. (c)* 0(7), p.1989-1992, (2003)
- M.V. Bogdanov, D.Kh. Ofengeim, A.I. Zhmakin, Industrial Challenges for Numerical Simulation of Crystal Growth, *Centr. Eur. Jour. Phys.* 2 (1), p.183-203, (2004).
- A.V. Kulik, M.V. Bogdanov, S.Yu. Karpov, M.S. Ramm, Yu.N. Makarov, Theoretical Analysis of the Mass Transport in the Powder Charge in Long-Term Bulk SiC Growth, *Mat. Sci. Forum* 457-460, p.67-70, (2004).
- A.K. Semennikov, S.Yu. Karpov, M.S. Ramm, A.E. Romanov, and Yu.N. Makarov, Analysis of threading dislocations in wide-bandgap hexagonal semiconductors by energetic approach, *Materials Science Forum* 457-460, p.383-386, (2004).
- E. Mokhov, S. Smirnov, A. Segal, D. Bazarevsky, Yu. Makarov, M. Ramm, and H. Helava. Experimental and Theoretical Analysis of Sublimation Growth of Bulk AIN Crystals. *Materials Science Forum* 457-460, p.1545-1548, (2004).



Conclusions

VR-PVT AIN[™] is an effective tool for simulation of long-term sublimation growth of bulk AIN crystals

Any questions concerning Virtual Reactor software tools can be sent to **vr-support@str-soft.com**

General presentation demonstrating capabilities of the Virtual Reactor software package and presentations demonstrating other editions of Virtual Reactor family, such as

- VR-PVT SiC™
- HEpiGaNS™
- VR-CVD SiC™

are available upon request